Influence of random roughness on cantilever curvature sensitivity

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Erratum: "Influence of random roughness on cantilever curvature sensitivity" [Appl. Phys. Lett. 96, 041912 (2010)]

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Due to error Figs. 2 and 3 (and captions) shown in the published paper are not the correct ones. Results, discussion, and conclusions of the paper remain unaltered by this correction.

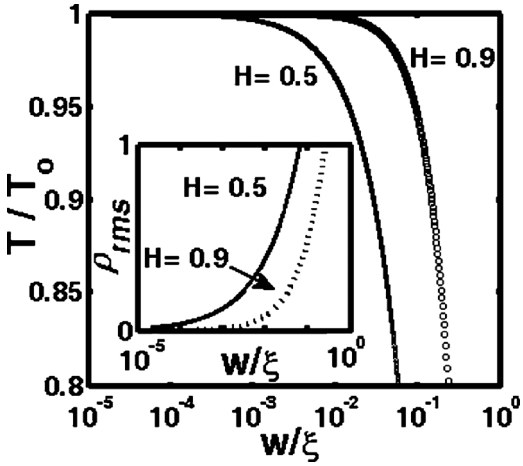

FIG. 2. Cantilever sensitivity T/T_0 as a function of long wavelength roughness ratio w/ξ for $w=1$ nm, different roughness exponents H, and Poisson ratio $v^L=0.18$ [corresponding to Si(111)]. The inset shows the dependence of the average local surface slope on the roughness ratio w/ξ for different roughness exponents H.

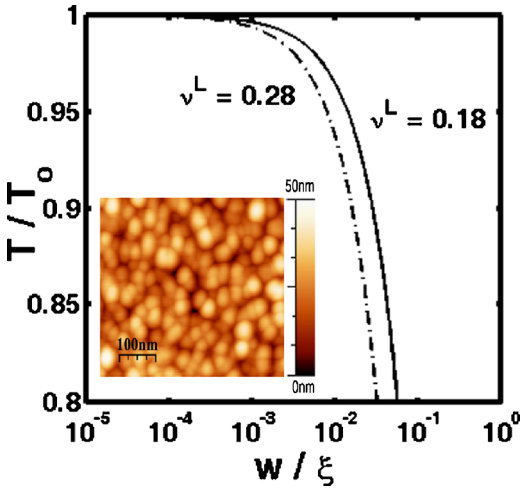

FIG. 3. (Color online) Cantilever sensitivity T/T_0 as a function of long wavelength roughness ratio w/ξ for $w=1$ nm, $H=0.5$, and two different Poisson ratios, $v^L=0.18$ [corresponding to Si(111)] and $v^L=0.28$ [corresponding to Si(100)]. The inset shows a typical gold rough surface deposited onto Si with $H=0.9$, $w=7$ nm, and $\xi=30$ nm yielding $w/\xi=0.23$.

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